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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPLICATION		FILING DATE		CLASS	SUBCLASS	GAU	EXAMINER				
APPL NUM	10077072	FILING DATE	02/14/2002	CLASS	315	SUBCLASS	111.21	GAU	2817	EXAMINER	lll
**APPLICANTS: Fischer Andreas; Trussell Dave; Kennedy Bill; Loewenhardt Peter;											
**CONTINUING DATA VERIFIED: None											
** FOREIGN APPLICATIONS VERIFIED: None											
PG-PUB <input type="checkbox"/> DO NOT PUBLISH <input type="checkbox"/> RESCIND <input type="checkbox"/>											
Foreign priority claimed <input type="checkbox"/> yes <input checked="" type="checkbox"/> no											
35 USC 119 conditions met <input type="checkbox"/> yes <input checked="" type="checkbox"/> no											
Verified and Acknowledged Examiners's initials <i>MR</i>											
ATTORNEY DOCKET NO P0877											
TITLE : Plasma processing apparatus and method for confining an RF plasma under very high gas flow and RF power Density conditions											
U.S. DEPT. OF COMM. / PAT. & TM-PTO-425L (Rev. 12-94)											

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
Assistant Examiner		Total Claims	Print Claim for O.G.
ISSUE FEE		DRAWING	
Amount Due	Date Paid	Sheets Drwg.	Figs. Drwg.
Primary Examiner		Print Fig.	
PREPARED FOR ISSUE		Application Examiner	
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